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## Descriptipn 描述

RTAC-SP系列真空镀膜机是多弧离子镀与磁控溅射完美结合的复合式镀膜设备。应用于五金件;玻璃、陶瓷工艺品等;电子产品,洁具,手表;高端奢侈品配件件:箱包拉链,鞋扣件,腰带等。

设备特点:系统稳定,重复性高,维护方便,良品率高。此外,设备弧阴极、溅射阴极安装法兰及离子源安装法兰可根据工艺需求进行互换,保证设备的灵活性和设备升级。

RTAC-SP设备可适用于各种靶材:无论金属还是介质,化合材料都可以利用此复合工艺进行镀膜。所成膜层具有膜层附着力强,较高硬度,耐磨损,防腐蚀;致密度高,重复度及颜色一致性好等特点。可镀制 铬色,黑色,银色,蓝色,七彩色等。为追求高端质量镀膜产品的供应商提供可靠保证。

RTAC-SP series coating equipment is a perfect combination of arc plating and sputtering

镀膜产品的供应商提供可靠保证。

a future upgrade.

deposition. Applied with hardware, glass and ceramic products, consumer electronics, sanitary appliance and watch, high end luxury products accessories: handbag chains, shoes buttons, belts etc. **Equipment features:** ease maintenance, repeatable, stable and high yield throughput. The deposition cathodes ( cathode arcs and sputtering cathodes) mounting flanges and ion

RTAC-SP coater has no limit on the coating materials: metals, dielectric coating, compound materials all can be deposited. The films are high hardness, excellent corrosion, wear resistance, high density and uniformity.

Coating colors: chrome , black, gold, silver, blue and rainbow colors etc.

source mounting flange are exchanged flexibly based on the coating processes demand for

RTAC-SP coater ensures manufactures to provide reliable coating quality for theirs customers who are pursing high-class coating finishing continually.

Ion Source

工艺需求

Cycle Time

**Bias Power** 

## ASC Standard 标准镀膜设备

Size(mm)

Number of

Model

型号	它人	Planetary Rods 行星体转轴数量	Sources 弧源数量	溅射阴极	离子源	镀膜周期	Supply(kVA) 偏压电源
RTAC950-SP	Ф950хН1350 2-door 双开门	3	8	4 Planar 4支平面靶	Linear Anode 线性阳极层		1*36
RTAC1213-SP	Φ1250xH1350 2-door 双开门	48	8	4 Planar 4支平面靶	Linear Anode 线性阳极层	30'~150' depends on substrates 30~150分,	1*30, AE
RTAC1250-SP	Ф1250хН1250	6,8,12,16	8	4~8 Cylinder 4~8支柱靶	depends oncoating process and	由产品决定	1*36
RTAC1008-SP	Ф1000хН800	3	6	2Cylinder 2支柱靶	product 取决于产品和		1*24

Cathodic Arc Sputtering Cathodes

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Model 型号	Size(mm) 尺寸	Number of Planetary Rods 行星体转轴数量	Cathodic Arc Sources 弧源数量	Sputtering Cathodes 溅射阴极	Ion Source 离子源	Cycle Time 镀膜周期	Bias Power Supply(kVA) 偏压电源
RTAC0808-SP	Ф800хН800	6.8	4	2~4 Cylinder or Planar 2~4平面或柱靶	Linear Anode 线性阳极层	30'~150'depends on substrates 30 ~150分, 由产品决定	2*48
RTAC1315-SP	Ф1300хН1500	24	6~9	2~8 Cylinder or Planar 2~8平面或柱靶	Linear Anode 线性阳极层		1*48